

**Amendments to the Claims:** This listing of claims will replace all prior versions, and listings, of claims in the application

Listing of Claims:

1.-13. (Cancelled).

14. (Previously Cancelled).

15.-61. (Cancelled).

62. (Previously Cancelled).

63.-77. (Cancelled).

78. (New) A method for producing an optical element, comprising:

a step of forming a proton exchange layer in an  $\text{LiNb}_x\text{Ta}_{1-x}\text{O}_3$  ( $0 \leq X \leq 1$ ) substrate;

a high-temperature annealing step of performing a heat treatment for the substrate at a temperature of  $150^\circ\text{C}$  or higher; and

a low-temperature annealing step of performing a heat treatment for the substrate at a temperature of  $120^\circ\text{C}$  or lower for 1 hour or more so as to mitigate strain introduced in the proton exchange layer by the high-temperature annealing step.

79. (New) A method for producing an optical element according to claim 78, wherein the low-temperature annealing step is performed at a temperature equal to or higher than  $50^\circ\text{C}$  but lower than or equal to  $90^\circ\text{C}$ .

80. (New) A method for producing an optical element according to claim 78, wherein the low-temperature annealing step comprises a step of gradually lowering the temperature from  $100^\circ\text{C}$  to  $60^\circ\text{C}$  over 30 hours.

81. (New) A method for producing an optical element according to claim 78, further comprising:

a step of forming a plurality of periodically-arranged domain inverted layers in the substrate.

82. (New) A method for producing an optical element, comprising:

a step of performing a proton exchange process for an  $\text{LiNb}_x\text{Ta}_{1-x}\text{O}_3$  ( $0 \leq X \leq 1$ ) substrate;

a first annealing step of performing a first heat treatment for the substrate at a first temperature, after performing the proton exchange process; and

a second annealing step of performing a second heat treatment for the substrate at a second temperature, after performing the first heat treatment,

wherein the second temperature is lower than the first temperature by 200°C or more.

83. (New) A method for producing an optical element according to claim 82, wherein the second annealing step is performed at a temperature equal to or higher than 50°C but lower than or equal to 90°C.

Respectfully submitted,

*Daniel N. Calder*

**Daniel N. Calder, Reg. No. 27,424**  
Attorney for Applicants

DNC/vj

Dated: November 13, 2003

☒ P.O. Box 980  
Valley Forge, PA 19482  
(610) 407-0700

☐ P.O. Box 1596  
Wilmington, DE 19899  
(302) 778-2600

**EXPRESS MAIL**

Mailing Label Number:

EV351885009US

Date of Deposit:

November 13 2003

I hereby certify that this paper and fee are being deposited, under 37 C.F.R. § 1.10 and with sufficient postage, using the "Express Mail Post Office to Addressee" service of the United States Postal Service on the date indicated above and that the deposit is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*Kathleen Libby*

Kathleen Libby